

Mikhail Rudenko

List of Publications by Year in descending order

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9
papers

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citations

2258059

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2272923

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all docs

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docs citations

9
times ranked

27
citing authors

#	ARTICLE	IF	CITATIONS
1	Plasma Instability of 2D Electrons in a Field Effect Transistor with a Partly Gated Channel. International Journal of High Speed Electronics and Systems, 2016, 25, 1640015.	0.7	12
2	Monte Carlo Simulation of Defects of a Trench Profile in the Process of Deep Reactive Ion Etching of Silicon. Russian Microelectronics, 2019, 48, 157-166.	0.5	4
3	Numerical Simulation of Cryogenic Etching: Model with Delayed Desorption. Russian Microelectronics, 2021, 50, 54-62.	0.5	3
4	Analytic Model of Transit-Time Diodes and Transistors for the Generation and Detection of THz Radiation. Russian Microelectronics, 2018, 47, 290-298.	0.5	2
5	Instrumented wafer as a Langmuir multiprobe tool for lateral plasma homogeneity measurements in processing plasma reactors. , 2013, , .		0
6	Single-electron solitons in magnetic field. Proceedings of SPIE, 2016, , .	0.8	0
7	Barrier-injection transit-time diodes and transistors for terahertz generation and detection. , 2019, , .		0
8	Sidewall defects in deep cryogenic Si etching in SF ₆ /O ₂ plasma: a numerical simulation. , 2019, , .		0
9	On temperature and flux dependence of isotropic silicon etching in inductively coupled SF ₆ plasma. Vacuum, 2022, 204, 111326.	3.5	0